

# **ION BEAM DEPOSITION SYSTEM**

## **ION BEAM DEPOSITION (IBD)**

## **ION BEAM ASSISTED DEPOSITION (IBAD)**

### **STANDARD FEATURES:**

Electro-Polished Stainless Steel Chamber D-Shaped Box)  
 4" Diameter View Port on Front Door with Manual Shutter  
 Turbo Molecular Vacuum Pumping System with Matching Dual Stage Rotary Vane Pump  
 Ion Beam Deposition with Convergent Beam Ion Source & Power Supply, with Easy Target Mounting Assembly  
 Ion Beam Assisted Deposition with Divergent Beam Ion Source & Power Supply  
 Quartz Crystal Thickness Sensor with Deposition Controller  
 Mass Flow Controller with Digital Readout  
 Full Range Vacuum Gauge with Digital Display & Readout  
 PLC Controlled System



### **OPTIONAL FEATURES:**

Water Chiller  
 Load Lock System with Sample Transfer Adaptability  
 Multi-Axis Substrate Stage Rotation  
 Quartz Lamp Heater (from 300° C up to 800° C)  
 Planetary Substrate Stage  
 PC Controlled System  
 Water Cooled Substrate Stage

Adjustable Size & Height Available for Substrate Stage  
 SQC 310 Film Thickness Monitor & Deposition Controller  
 Motorized Shutter Assembly  
 Dry Scroll Pump  
 Cryo Pumping System  
 Cold Cathode or Hot Cathode Ionization Gauge  
 Additional Spare Flanges for Future Upgrades  
 RF Cleaning/Biasing Capability  
 In Situ Mask Changer



1 Torr = 1 mm Hg

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